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Date of Signature and Deposit: November 14, 2002

Fee OK

Adam J. Zimm  
Attorney of Record

# 8/a

12-26-02

L. Spruell

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Richard D. Harris, et. al.  
Serial No.: 09/967,157  
Filed: September 28, 2001  
For: Method for fabricating a microelectromechanical system (MEMS) device using a pre-patterned bridge  
Group Art Unit: 2812  
Docket No.: 110003.97630

AMENDMENT

Box Amendment  
Commissioner for Patents  
Washington, D. C. 20231

Dear Sir:

In response to the Office Action dated August 14, 2002, please amend the above-identified patent application as follows:

IN THE CLAIMS:

The following revised claims should be substituted for the like numbered claims that were filed with the patent Application. Claims 15, 24, 33, 49, and 50 should be cancelled from the application. New claims 53-102 should be added to the application. A version of the claims with markings to show changes made is attached to the end of this document.

1. (Once Amended) A method of fabricating a MEMS structure, comprising the steps of:

- (a) providing a wafer having at least a first layer and a second layer;
- (b) removing a portion of the first layer through to the second layer to form a bridge member;
- (c) after step (b), attaching the wafer to the upper surface of a substrate to form a composite structure having an internal void formed therein, wherein the

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